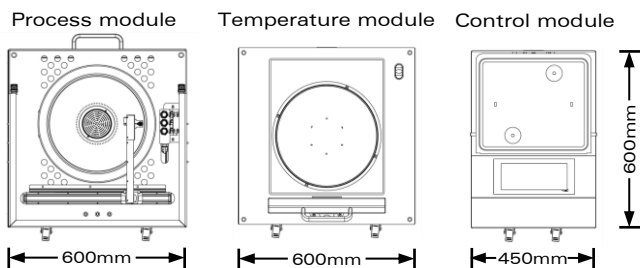


Single wafer processing.

Semi-automated coating, developing, cleaning & lift-off

The modular amcossamr semi-automated stand-alone spinner is the perfect device for single-wafer processes for substrate sizes between 2" and 300 mm. With its very flexible fields of application in coating, lift-off, developing, cleaning, vapor priming and heating it brings special benefit to R&D laboratories and other facilities with small-lot production and single process steps.



All amr modules have the same compact footprint (besides the control module which is even smaller). This makes the room required easily projectable and saves expensive facility/laboratory space.



amr 200 **amr 300**

Beneficial highlights_

// **Full process control:** each selected process is managed by the relevant module of our comfortable amcoss amspILOT software complying with Semi-standard E95-1101. All necessary parameters can be adjusted and will be logged into the software.

// **SECS/GEM interface:** the tool can be equipped with a SECS/GEM interface or other customized protocols.

// **High-quality hardware:** taking the same proven high-quality, standard industry-components as used for our fully automated amcoss amc tools, ensures reliability in operation, long lifetime, good serviceability and a very attractive price-performance-ratio.

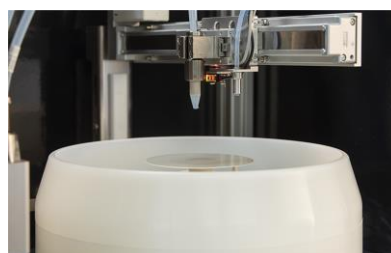
// **Safe:** designed accordingly to the newest safety rules.



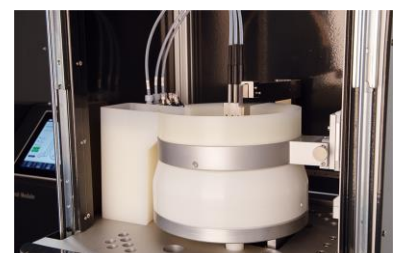
// Optionally, a very compact, autonomous table-top temperature module is available.



// Solvent module for lift-off or resist strip for standard solvents and various lift-off techniques



// Coater module with optimized bowl and exhaust for best uniformity and repeatability



// Developer module with high splash ring for spray and puddle developing.

Modular system for customer-specific equipment_

Our amcoss amr series is a completely modular system. The control module, which contains the controlling system, can be combined flexibly with one or several selected processing modules (coater, cleaner, developer, lift-off, hot-/coolplate, vapor priming hotplate, media cabinet) according to customer needs or process requirements. So, we are able to create a tool meeting the individual needs of every single client.

amrcontrol module

- // Controlling system with **amsPILOT** software for the steering and easy use of the connected processing modules
- // Recipes are compatible with **amcoss amc** equipment
- // 10" colour touch screen with IPC
- // Tray for easy handling of wafers
- // Easy access to components in the module's interior



amrdeveloper module

- // Spray-, puddle or megasonic development
- // Various developer media per bowl possible
- // Servo-controlled nozzle positioning programmable with absolute distance values
- // Programmable wafer backside, topside and bowl rinse



amrcoater module

- // Unique bowl design for optimal process results (e.g. no cotton candy when processing high viscosity resists)
- // Servo-controlled nozzle positioning, programmable with absolute distance values
- // Programmable wafer backside and bowl rinse
- // EBR (Edge Bead Removal) system programmable with absolute distance values, also for rectangular substrates
- // Dispense system for up to 5 different media per bowl with single-nozzle positioning arm and automatic nozzle change



amrcleaner module

- // Cleaning of wafer frontside, backside and edge bevel
- // Various cleaning methods as standard solution available
- // Suitable to work with different diluted chemicals
- // Programmable wafer backside, topside and bowl rinse



amrlift-off module

- // Unique lift-off process with large-area megasonic or high-pressure
- // High- or middle-pressure cleaning with DIW or solvents
- // Special reclaim solution for very low media consumption
- // Easy recycling of lifted metals
- // Programmable wafer backside, topside and bowl rinse



amrtemperature module

- // Standard hotplate (60° - 200°C)
- // High-temperature hotplate (60° - 450°C)
- // HMDS vapor priming hotplate (60° - 200°C)
- // Single or multi-zone hotplate
- // Coolplate (10° - 60°C), with either water or Peltier cooling
- // Curing by UV light or supported by UV light
- // Options for proximity control: Fixed proximity, programmable proximity, vacuum contact



amrmedia module

- // Cabinet made of stainless steel with drawer
- // Integrated exhaust connector
- // Safety trip pan with leakage sensor
- // Supply of different media to the system

